Guide to Magnification Calibration and other Test Specimens



Traceable Calibration is now available for the 301BE, 150-2D, 150-1D, and 70-1D specimens, as models 292 UTC, 150-2DUTC, 145 TC, and 70-1DUTC. This helps you achieve higher quality and meet ISO-9000 and 14000 requirements. What does traceability mean?

The calibration certificate for ordinary specimens gives an average pitch value based on batch measurements. In contrast, the certificate of traceable calibration reports the average pitch value and the uncertainty of single pitch values, based on individual measurements of the actual specimen and the measurements are traceable to the international meter. Our traceability path for 70-1DUTC is via NIST. Our traceability path for 150-2DUTC, 145TC and 292UTC is via PTB, the German counterpart of NIST. This is equivalent to NIST traceability, based on a mutual recognition agreement for nanoscale measurements among NIST, PTB, and other leading national measurement labs.

Application	Model		Pattern		Pitch		Material		Mounting		Rema	Remarks				
					(nm) ¹											
AFM, SEM, Auger, Etc.	70-1DUTC		parall ridge:	lel S	70		SiO2 lines on Si		Unmounted, on steel disk, or on an SEM stub (extra charge)		use contact or tapping mode. Works well in SEM.			е.		
AFM, SEM, Auger, etc.	150-2D 150-2D	and UTC	Array round bump	rray of unded 144 umps		Al bumps on Si		Unmounte disk, or on stub (extra	d, on steel an SEM charge)	use contact or tapping mode. Works well in SEM.						
AFM,SEM ² , TOF-SIMS, Auger ² , Surface Potential, other material contrast techniques. SNOM ⁵ .	150-1D and 145TC		Paral ridge:	lel s	144		Al lines on Glass		unmounted disk	l or on stee	use contact or tapping mode. Try it in SNOM and in two- photon or multi-photon confocal optical microscopy.					
AFM,SEM, TOF-SIMS, Auger, Surface Potential, other material contrast techniques	301BE and 292UTC		parall ridge:	lel s	292		Ti lines	s on Si	unmounted disk, or on stub (extra	l, on steel an SEM charge)	use contact or TappingMode. Works well in SEM SEI and BEI modes. (secondary and back- scatter electron imaging)					
AFM	300-1D		Paral ridge:	lel s	288		W-coated Photoresist on Si		15 mm ste	el disk	use contact or TappingMode.					
AFM	300-2D and 302-edu		Array Posts	ay of ts 297		Al bumps on Si		15 mm steel disk		use con	use contact or TappingMode					
AFM	700-1D		Parallel 700			W-coated Photoresist on Si		15 mm steel disk		use contact or TappingMode						
AFM	700-2D		Array of Posts 700		700		W-coated Photoresist on Si		15 mm steel disk		use TappingMode					
FM, SEM, extreme nvironments 750-HD		Array of flat bumps		750 (X), Z (100)		Ni		unmounted		High Durability: TappingMode, Contact Mode, STM, Liquid, High Temperature						
AFM, nanomechanics and nanofluidics		Parallel channels		channels 370 nm wide, 180 nm deep)		Ni		unmounted		High Durability: TappingMode, Contact Mode, STM, Liquid, High Temperature Not a calibration grating						
AFM Phase Imaging PT		random hard and soft domains as small as 10 nm		none	* 1	polymer		15 mm steel disk		test reso confide	test resolution and build confidence in phase imaging					
Specimen Compatibility: SEM, AFM and STM scanning modes and Special Environments																
70-	70-1DUTC 30		1BE UTC	1 150-2	50-2D	30 30	300-2D)2-edu	150-1 145T	D 300-1D C	700-1D	700-2D	750-HD	751-HD	PT		
TappingMode [™]	Yes		Yes		Yes		Yes	Ye	es Yes	Yes	Yes	Yes	Yes	Yes		

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Yes	Yes	Yes	Yes	Yes	Yes	Yes	Yes	Yes	Yes	Yes
Yes	Yes	Yes	Yes	Yes	Yes	Yes	No	Yes	Yes	Yes
No	No	Yes ³	Yes ³	No	No	No	No	Yes	Yes	No
Not tested	Not tested	Not tested	Not tested	Not tested	No	No	No	Yes	Yes	Yes
Not tested	Not tested	Not tested	Not tested	Not tested	No	No	No	Yes	Yes	No
Yes	Yes	Yes	Yes	No	Yes	Yes	Yes	Yes	Yes	No
	Yes Yes No Not tested Not tested Yes	YesYesYesYesYesYesNoNoNot testedNot testedNot testedNot testedYesYes	Yes Yes Yes Yes Yes Yes Yes Yes Yes No No Yes ³ Not tested Not tested Not tested Not tested Not tested Not tested Yes Yes Yes	YesYesYesYesYesYesYesYesYesYesYesYesNoNoYes³Yes³Not testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedYesYesYesYes	YesYesYesYesYesYesYesYesYesYesYesYesYesYesYesNoNoYes³Yes³NoNot testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedYesYesYesYesYesNo	YesYesYesYesYesYesYesYesYesYesYesYesYesYesYesYesYesNoNoYes³Yes³NoNoNot testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedNot testedNotNot testedNot testedNot testedNot testedNoYesYesYesYesNo	YesNoNoYes³Yes³NoNoNoNot testedNot testedNot testedNot testedNot testedNoNoNot testedNot testedNot testedNot testedNoNoNoYesYesYesYesYesNoNoYesYesYesYesNoYesYes	YesNoNoNoYes³Yes³NoNoNoNoNot testedNot testedNot testedNot testedNoNoNoNot testedNot testedNot testedNot testedNoNoNoYesYesYesYesYesNoYesYesYesYesYesYesNoYesYes	YesNoNoYes³Yes³NoNoNoNoYesNot testedNot testedNot testedNot testedNot testedNoNoYesNot testedNot testedNot testedNot testedNoNoYesYesYesYesYesYesYesYesYesYesYesYesYesNoYesYesYes	YesNoNoYes³Yes³NoNoNoNoYesNot testedNot testedNot testedNot testedNoNoNoYesNot testedNot testedNot testedNot testedNoNoNoYesYesYesYesYesYesNot testedNot testedNoNoNoYesYesYesYesYesYesYesNoYesYesYesYes

Notes

¹Pictor values are stated as a guide. Please refer to the calibration certificate shipped with each specimen. ²may require a conductive coating for SEM or Auger use. ³A conductive coating may be required for STM imaging. ⁴Available unmounted or mounted (extra cost - please specify desired stub).

⁵SNOM is Scanning Near-field Optical Microscopy, sometimes called NSOM (near-field scanning optical microscopy).



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